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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.		
09/667,777	09/22/2000	Mitsuaki Komino	08038.0044	1267		
75	90 <b>*</b> 12/26/2001					
Finnegan Henderson Farabow Garrett & Dunner LLP 1300 I Street NW Washington, DC 20005-3315			EXAMI	EXAMINER		
			ZERVIGON, RUDY			
			ART UNIT	PAPER NUMBER		
			1763	Z		
			DATE MAILED: 12/26/2001			

Please find below and/or attached an Office communication concerning this application or proceeding.

					MI- 7			
•		Application No.		Applicant(s)	<u> </u>			
		09/667,777		KOMINO ET AL.				
Offic	Action Summary	Examiner	1	Art Unit	<u> </u>			
		Rudy Zervigon	1	1763				
The MAIL Period for Reply	ING DATE of this communication app	pears on the cover	sheet with the cor	respondence ad	ddress			
THE MAILING C  - Extensions of time in after SIX (6) MONTI  - If the period for reply  - If NO period for reply  - Failure to reply within  - Any reply received by	O STATUTORY PERIOD FOR REPLY DATE OF THIS COMMUNICATION. In the available under the provisions of 37 CFR 1.1 HS from the mailing date of this communication. It is specified above is less than thirty (30) days, a reply is specified above, the maximum statutory period in the set or extended period for reply will, by statute by the Office later than three months after the mailing adjustment. See 37 CFR 1.704(b).	36(a). In no event, hower within the statutory min will apply and will expire to cause the application to	ver, may a reply be timely imum of thirty (30) days w SIX (6) MONTHS from the become ABANDONED	y filed  will be considered time mailing date of this of (35 U.S.C. § 133).				
1) Respons	ive to communication(s) filed on 22 S	<u>September 2000</u> .			,			
2a) ☐ This action	on is <b>FINAL</b> . 2b)⊠ Th	is action is non-fi	nal.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.								
Disposition of Clai	ms							
4) Claim(s)	<u>1-26</u> is/are pending in the application	<b>.</b>						
4a) Of the	above claim(s) is/are withdraw	wn from considera	ation.					
5)	is/are allowed.							
6)⊠ Claim(s) <u>1</u>	-3,5-14,16-23 and 25 is/are rejected	,						
7)⊠ Claim(s) <u>4</u>	1,15,24 and 26 is/are objected to.							
8) Claim(s) _	are subject to restriction and/o	r election requirer	nent.					
<b>Application Papers</b>	<b>:</b>							
9)☐ The specifi	cation is objected to by the Examine	<b>r</b> .'						
10) The drawin	g(s) filed on is/are: a)□ accep	oted or b) Objecte	ed to by the Exami	ner.	•			
Applicant	may not request that any objection to the	e drawing(s) be held	d in abeyance. See	37 CFR 1.85(a).				
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.								
If approved, corrected drawings are required in reply to this Office action.								
12) The oath or	r declaration is objected to by the Ex	aminer.			•			
Priority under 35 U	.S.C. §§ 119 and 120							
13) Acknowled	dgment is made of a claim for foreign	priority under 35	U.S.C. § 119(a)-(	d) or (f).				
a)∏ All b)[	] Some * c)☐ None of:							
1.☐ Ceri	tified copies of the priority documents	s have been rece	ved.					
2.☐ Ceri	tified copies of the priority documents	s have been recei	ved in Application	No				
	ies of the certified copies of the prior application from the International Bu ached detailed Office action for a list	reau (PCT Rule 1	7.2(a)).	in this National	Stage			
14) Acknowledg	ment is made of a claim for domesti	c priority under 35	5 U.S.C. § 119(e) (	(to a provisiona	application).			
•	anslation of the foreign language pro gment is made of a claim for domesti							
Attachment(s)								
· ·	es Cited (PTO-892) rson's Patent Drawing Review (PTO-948) sure Statement(s) (PTO-1449) Paper No(s)	5) 🔲	Interview Summary (P Notice of Informal Pate Other:					
S. Patent and Trademark Office PTO-326 (Rev. 04-01)	Office Ac	tion Summary		Part o	f Paper No. 7			

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#### **DETAILED ACTION**

# Claim Rejections - 35 USC § 112

- 1. The following is a quotation of the second paragraph of 35 U.S.C. 112:
  - The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.
- 2. Claims 1, 7, 12, 13, and 17 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Claim 1 requires "a base metal (page 8, lines 24-26; application specification) in which the heater and the ceramic-metal composites are cast". The Examiner believes that there are two possible interpretations for this requirement in light of the specification:
- a) The heater and the ceramic-metal composites have a common "base-metal", i.e. the composites and heater are cast<sup>1</sup> from a common "base-metal".
- b) The heater and the ceramic-metal composites are formed within and are contained by a "base-metal", i.e. the composites and heater are cast<sup>2</sup> in a "base-metal".

The Examiner believes that the specification, as cited from page 8, supports the use/misuse of "cast" as pertaining to composition:

"Then, molten <u>aluminum</u> as a base metal is poured into the mold 48 to infiltrate the porous SiC blocks 50, 52 with molten <u>aluminum</u>."

For the remainder of the action, the Examiner will interpret "cast" per the specification's usage pertaining to composition.

<sup>&</sup>lt;sup>1</sup> n 2a: the form in which a thing is constructed. Merriam-Webster's Collegiate Dictionary - 10th Ed. p.178 – Form, here, is interpreted as composition in light of page 8 of the specification

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# Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.
- 2. Claims 1-3, 5-14, 16-23, and 25 are rejected under 35 U.S.C. 102(e) as being anticipated by Hirano et al (U.S.Pat. 6,120,661). Hirano et al teaches a method of casting an electrode wherein a heater is formed from molten aluminum forming a ceramic-metal composite (column 5, lines 17-31). Further, Hirano et al teaches:
- 1. An electrode (10; Figure 1A) comprising: a heater (15; Figure 1A; column 16, lines 23-38) arranged on a plane; a pair of ceramic-metal composites (11; Figure 1A; column 15, lines 56-65) each arranged above and below the heater respectively so that the heater is positioned therebetween; and a base metal (page 8, lines 24-26; application specification "matrix" column 4, lines 51-65) in which the heater and the ceramic-metal composites are cast Hirano et al teaches Ti or stainless steel (containing aluminum) for the heater's material (column 12, lines 38-51) to match the thermal expansion of the supporting stage (10). Further, Hirano et al teaches 2.5% by weight of TiO<sub>2</sub> as a constituent of the ceramic layer 13 (column 18, line 66 column 19, line 24) forming the supporting stage 10A that is also Al<sub>2</sub>O<sub>3</sub>
- 2. An electrode comprising: a heater arranged on a plane; a core metal plate (14) arranged substantially parallel to the plane and adjacent to the heater; and a base metal (Titanium) in which the heater and the core metal are cast.
- 3. The electrode according to claim 2, wherein a plurality of base metal communication holes (Figure 1C) are formed through the core metal plate (14).
- 5. The electrode according to claim 2, wherein the electrode is configured so that a high frequency voltage (32, Fig.13) is applied thereto.

<sup>&</sup>lt;sup>2</sup> VT **4a:** to give a shape to (a substance) by pouring in liquid or plastic form and letting harden without pressure. Merriam-Webster's Collegiate Dictionary - 10th Ed. p.178

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- 6. A susceptor comprising; a heater (15) arranged on a plane; upper and lower ceramic-metal composites (11; Figure 1A; column 15, lines 56-65) arranged so that the heater is positioned therebetween; and a ceramic electrostatic chuck (14, column 16, lines 23-38 "brazing material", column 14, lines 23-26) that attracts and holds an object to be treated, the electrostatic chuck having a coefficient of linear thermal expansion substantially the same as that of the upper ceramic-metal composite (column 14, lines 31-38), and being joined to an upper surface of the upper ceramic-metal composite.
- 7. The susceptor according to claim 6 further comprising a base metal in which the heater and the upper and lower ceramic-metal composites are cast per the claim 1 citation:(page 8, lines 24-26; application specification "matrix" column 4, lines 51-65) in which the heater and the ceramic-metal composites are cast Hirano et al teaches Ti or stainless steel (containing aluminum) for the heater's material (column 12, lines 38-51) to match the thermal expansion of the supporting stage (10). Further, Hirano et al teaches 2.5% by weight of TiO<sub>2</sub> as a constituent of the ceramic layer 13 (column 18, line 66 column 19, line 24) forming the supporting stage 10A that is also Al<sub>2</sub>O<sub>3</sub>
- 11. The susceptor according to claim 6, wherein the susceptor is configured so that a high frequency voltage (32, Fig.13) is applied thereto.
- 12. A plasma processing apparatus comprising: a processing vessel (Figures 2,4,5,6, and 7); an electrode (10; Figure 1A) including: a heater (15; Figure 1A; column 16, lines 23-38) arranged on a plane; a pair of ceramic-metal composites (11; Figure 1A; column 15, lines 56-65) each arranged above and below the heater so that the heater is positioned therebetween: and a base metal in which the heater and the ceramic-metal composites are cast per the claim 1 citation:(page 8, lines 24-26; application specification "matrix" column 4, lines 51-65) in which the heater and the ceramic-metal composites are cast Hirano et al teaches Ti or stainless steel (containing aluminum) for the heater's material (column 12, lines 38-51) to match the thermal expansion of the supporting stage (10). Further, Hirano et al teaches 2.5% by weight of TiO<sub>2</sub> as a constituent of the ceramic layer 13 (column 18, line 66 column 19, line 24) forming the supporting stage 10A that is also Al<sub>2</sub>O<sub>3</sub>

and a high frequency power sources that applies a high frequency voltage (32, Fig.13) to the electrode (10; Figure 1A).

- 13. A plasma processing apparatus comprising: a processing vessel, an electrode (10; Figure 1A) including: a heater (15; Figure 1A; column 16, lines 23-38) arranged on a plane; a core metal plate (14) arranged substantially parallel to the plane and adjacent to the heater: and a base metal in which the heater and the ceramic-metal composites (11; Figure 1A; column 15, lines 56-65) are cast; and a high frequency power source (32, Fig.13) that applies a high frequency voltage to the electrode.
- 14. The apparatus according to claim 13, wherein a plurality of base metal communication holes (Figure 1C) are formed through the core metal plate.

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- 16. A plasma processing apparatus comprising; a processing vessel, a susceptor (10, Fig.13) including: a heater (15; Figure 1A; column 16, lines 23-38) arranged on a plane: upper and lower ceramic-metal composites (11; Figure 1A; column 15, lines 56-65) arranged so that the heater is positioned therebetween: and a ceramic electrostatic chuck (14, column 16, lines 23-38 "brazing material", column 14, lines 23-26) that attracts and holds an object to be treated, the electrostatic chuck having a coefficient of linear thermal expansion substantially the same as that of the upper ceramic-metal composite (column 14, lines 31-38), and being joined to an upper surface of the upper ceramic-metal composite: and a high frequency power source (32, Fig.13) that applies a high frequency voltage to the susceptor.
- 17. The plasma processing apparatus according to claim 16, wherein the heater and the upper and lower ceramic-metal composites are cast in a <u>base metal</u> (page 8, lines 24-26; application specification "matrix" column 4, lines 51-65) in which the heater and the ceramic-metal composites are cast Hirano et al teaches Ti or stainless steel (containing aluminum) for the heater's material (column 12, lines 38-51) to match the thermal expansion of the supporting stage (10). Further, Hirano et al teaches 2.5% by weight of TiO<sub>2</sub> as a constituent of the ceramic layer 13 (column 18, line 66 column 19, line 24) forming the supporting stage 10A that is also Al<sub>2</sub>O<sub>3</sub>
- 18. The plasma processing apparatus according to claim 16, wherein the susceptor is provided with heat transfer gas passages (16) that supplies a heat transfer gas to a surface of the electrostatic, the passage passing through the susceptor.

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### Allowable Subject Matter

3. Claims 4, 15, 24, and 26 would be allowable if rewritten to overcome the rejections under 35 U.S.C. 112, second paragraph, set forth in this Office action and to include all of the limitations of the base claim and any intervening claims.

#### Conclusion

4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. U.S.Pat. 5,684,669; 5,571,366; 6,197,246.

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Rudy Zervigon whose telephone number is (703) 305-1351. The examiner can normally be reached on a Monday through Thursday schedule from 8am through 7pm. The official after final fax phone number for the 1763 art unit is (703) 872-9311. The official before final fax phone number for the 1763 art unit is (703) 872-9310. Any Inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Chemical and Materials Engineering art unit receptionist at (703) 308-0661. If the examiner can not be reached please contact the examiner's supervisor, Gregory L. Mills, at (703) 308-1633.

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